ABSTRACT OF THE DISCLOSURE

~~Disclosed is a~~ A fabricating method for a system including a plurality of processing apparatuses connected to each other by ~~means of~~ an inter-apparatus transporter~~, wherein one group of~~. The semiconductor waters are processed in the processing apparatuses and ~~other group of wafers~~ are transported to specified processing apparatuses ~~for a~~ in different time intervals ~~from (To+T) to a time To; and another group of wafers are processed and the remaining group of wafers are transported for a time interval from (To+T) to (To+2T). Since processing apparatuses can receive at least one of works from the inter-apparatus transporter for a time interval T min, the distribution of works from the transporter to processing apparatus is completed for the time interval T min. The transporter is emptied for each time interval T min, and works are unloaded to the emptied transporter, which makes easy the scheduling, control and management of the transporting of a plurality of works in the fabricating system. Moreover,~~ that are set to N times a unit time interval. ~~since~~ Since the fabricating system ~~including~~

includes processing apparatuses ~~is~~ and an inter-apparatus transporter that are periodically controlled at time intervals related to a ~~cycle~~ unit time ~~T min~~, intervals related to a unit time, the scheduling of a plurality of works can be made ~~easy,~~ efficiently to enhance the level of optimization, thus improving the productivity.